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ASML Netherlands B.V.

COMMUNICATION

The European Patent Office herewith transmits as an enclosure the European search report for the above-mentioned European patent application.

If applicable, copies of the documents cited in the European search report are attached.

☒ Additional set(s) of copies of the documents cited in the European search report is (are) enclosed as well.

The following specifications given by the applicant have been approved by the Search Division:

☐ abstract

☐ title

☒ The abstract was modified by the Search Division and the definitive text is attached to this communication.

The following figure will be published together with the abstract:

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REFUND OF THE SEARCH FEE

If applicable under Article 10 Rules relating to fees, a separate communication from the Receiving Section on the refund of the search fee will be sent later.





DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Cl.7)
X	EP 1 041 607 A (NIPPON KOGAKU KK) 4 October 2000 (2000-10-04) * abstract * * figures 1-3 * * paragraph '0002! * * paragraph '0030! - paragraph '0066! * -----	1-10	G03F7/20
X	US 5 153 419 A (TAKAHASHI KAZUHIRO) 6 October 1992 (1992-10-06) * abstract * * figures 2,3a,3b * * column 3, line 27 - column 4, line 66 * -----	1,10	
A	EP 1 107 068 A (ASM LITHOGRAPHY BV) 13 June 2001 (2001-06-13) * abstract * * figures 1,2 * * paragraph '0001! - paragraph '0002! * * paragraph '0007! - paragraph '0015! * * paragraph '0026! - paragraph '0032! * -----	2,3	
			TECHNICAL FIELDS SEARCHED (Int.Cl.7)
			H01L G03F
The present search report has been drawn up for all claims			
Place of search		Date of completion of the search	Examiner
The Hague		2 July 2004	Andersen, O
CATEGORY OF CITED DOCUMENTS			
X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document			

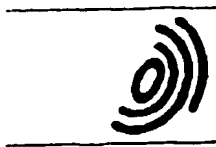
**ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.**

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This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report. The members are as contained in the European Patent Office EDP file on
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02-07-2004

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ABSTRACT / ZUSAMMENFASSUNG / ABREGE

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In a projection system (PL) for EUV, the positions of mirrors (M1-M6) are measured and controlled relative to each other, rather than to a reference frame. Relative position measurements may be made by interferometers or capacitive sensors (IF3-IF9) mounted on rigid extensions of the mirrors.